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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| In re New Patent Application of | |) | | 1 |
|---|--------------------------|----------------------|-------------------|---|
| Taketomi ASAMI et al. | |) | | |
| Japanese Priority Application No. 2000-131353 | |) Attn: Applications | | |
| Japanese Priority Date: April 28, 2000 | |) | Branch | |
| For: | MANUFACTURING METHOD FOR |) | | |
| | SEMICONDUCTOR DEVICE |) Dat | e: April 26, 2001 | |

PRELIMINARY AMENDMENT

Honorable Commissioner for Patents

Washington, D.C. 20231

Sir:

Please preliminarily amend the subject application as follows:

IN THE SPECIFICATION:

Please amend specification as follows: Please note that the specification is presented below in its amended form. It is further presented as an Attachment to the Amendment whereby the amendments to the specification are outlined using the conventional method of bracketing and underlining.

Please amend the BRIEF DESCRIPTION OF THE DRAWINGS on pages 4 and 5 as follows:

Figs. 2A, 2B, and 2C are cross sectional views of a TFT according to the example 1;

Figs. 3A, 3B, and 3C are cross sectional views of a TFT according to the example 1;